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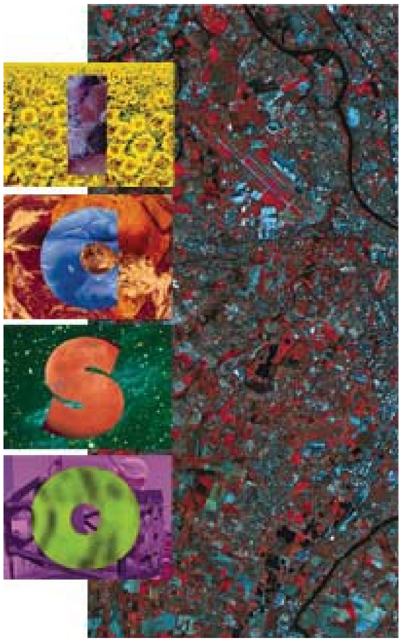

Computer assisted aspherical polishing: advantages and limits

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ABSTRACT

COMPUTER ASSISTED ASPHERICAL POLISHING : ADVANTAGES AND LIMITS

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SESO has increased by an important factor its capabilities of aspherical polishing with the technology of computer assisted polishing. The advantages and current limitations of this technology will be discussed :

- New performances obtained in terms of wavefront accuracy, mid-spatial-frequency errors, roughness,
- Capabilities to polish aspherical surface with low F number,
- The link to metrology development which is a critical part of polishing performances.